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## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Akio MISAKA

Application No.: 10/824,529

Filed: April 15, 2004



Customer Number: 20277

Confirmation Number: 6593

Group Art Unit: 1756

Examiner: ROSASCO, STEPHEN D

For: PHOTOMASK, PATTERN FORMATION METHOD USING PHOTOMASK AND MASK DATA CREATION  
METHOD FOR PHOTOMASK

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

Transmitted herewith is an Amendment in the above-identified application.

- ☒ No additional fee is required.  
☐ Applicant is entitled to small entity status under 37 CFR 1.27  
☐ Also attached:

The fee has been calculated as shown below:

	NO. OF CLAIMS	HIGHEST PREVIOUSLY PAID FOR	EXTRA CLAIMS	RATE	FEE
Total Claims	36	41	0	\$50.00 =	\$0.00
Independent Claims	3	3	0	\$200.00 =	\$0.00
Multiple dependent claims newly presented					\$0.00
Fee for extension of time					\$0.00
					\$0.00
Total of Above Calculations					\$0.00

- ☐ Please charge my Deposit Account No. 500417 in the amount of \$0.00. An additional copy of this transmittal sheet is submitted herewith.
- ☒ The Commissioner is hereby authorized to charge payment of any fees associated with this communication or credit any overpayment, to Deposit Account No. 500417, including any filing fees under 37 CFR 1.16 for presentation of extra claims and any patent application processing fees under 37 CFR 1.17.

Respectfully submitted,

McDERMOTT WILL &amp; EMERY LLP

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Date: August 17, 2007

Please recognize our Customer No. 20277 as our  
correspondence address.



Docket No.: 060188-0839

PATENT

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of	:	Customer Number: 53080
Akio MISAKA	:	Confirmation Number: 6593
Application No.: 10/824,529	:	Group Art Unit: 1756
Filed: April 15, 2004	:	Examiner: ROSASCO, STEPHEN D
For: PHOTOMASK, PATTERN FORMATION METHOD USING PHOTOMASK AND MASK DATA CREATION METHOD FOR PHOTOMASK		

**AMENDMENT**

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In response to the Office Action dated May 17, 2007, having a three-month shortened statutory period for response set to expire August 17, 2007, please amend the above-identified application as follows.

**AMENDMENTS TO THE TITLE:**

*Please amend the Title of the Invention as follows:*

~~PHOTOMASK, PATTERN FORMATION METHOD USING PHOTOMASK AND  
MASK DATA CREATION METHOD FOR PHOTOMASK~~